An Introduction to Electrochemical Impedance Spectroscopy (EIS)

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Excellent references:

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"Identification of Electrochemical Processes by Frequency Response Analysis" http://www.solartronanalytical.com/technicalsupport/technicalnotes/technote04.htm

"Basics of Electrochemical Impedance Spectroscopy" http://www.gamry.com/App_Notes/EIS_Primer/EIS_Primer_2007.pdf

Impedance Spectroscopy: Theory, Experiment, and Applications E. Barsoukov and J. R. Macdonald, Eds., Wiley-Interscience, 2005.

Basics

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- > We are interested in what happens at the interface between an SRF surface and a reactive media.
 - Chemical etching may occur spontaneously without electrical potential.
 - Addition of an <u>externally-defined potential</u> changes the dynamics of chemical reactions at the surface.
 - Such changes in the electrochemical dynamics at an interface are <u>extremely nonlinear</u>.
 - > We need appropriate process characterization tools.



- For <u>diagnostic purposes</u>, we want to characterize changes at a surface under specific system parameters.
- For <u>application purposes</u>, we want to tailor system parameters in order to obtain a desirable effect on a surface.
- ➢ EIS is a tool that bridges both purposes.
- EIS is a perturbative characterization of the dynamics of an electrochemical process.
 - > A tool for unraveling complex non-linear processes.





- Exploit Faraday's Law to <u>characterize a</u> <u>chemical process in terms of electrical</u> <u>measurements</u>.
- Electrochemical impedance is the response of an electrochemical system (cell) to an applied potential.
 - The frequency dependence of this impedance can reveal underlying chemical processes.





- > The response of electrochemical systems is <u>very</u> nonlinear.
- > We interrogate the impedance in a perturbative manner:
 - Small amplitude (~10 mV) AC ripple on top of the controlled DC polarization potential.
- The complex response of the system is usually displayed in Nyquist format, with the reactance inverted (since such systems are inherently capacitive).







Complex plane impedance spectrum - series resistance, capacitance - Complex plane impedance spectrum - parallel resistance, capacitance

- The response of the system as a function of the perturbation frequency can reveal internal dynamics.
- The <u>capacitance</u> at the metal/electrolyte interface always plays an important role.

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A process that depends on <u>diffusion</u> of reactants toward or away from the surface has a particular low-frequency character. ("Warburg" impedance)



Example: Anodic corrosion of <u>iron in sulfuric acid</u>



Electrochemical Impedance Spectroscopy

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- EIS is widely used as a standard characterization technique for many material systems and applications (corrosion, plating, batteries, fuel cells, etc.)
- PC-based modern DSP electronics+software packages now replace lock-in amplifier techniques for implementing EIS.



Gamry Instr. G 300



Example of EIS of niobium electropolishing with a particular parameter set.

See H. Tian's talk for more data and interpretation



Using Electrochemical Impedance Spectroscopy

EIS has been helpful for discerning the mechanism involved with electropolishing niobium.

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The Mechanism of Electropolishing of Niobium in Hydrofluoric–Sulfuric Acid Electrolyte

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- EIS may also be useful as an EP process characterization tool that aids in surface optimization and quality control.
 - Protocol development for engineered surface topography
 - On-line process feedback

